AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the present application.

Listing of Claims:

Claim 1 (currently amended): A holder for semiconductor as well as liquidcrystal manufacturing devices, the holder comprising:

a ceramic susceptor of a ceramic whose thermal conductivity is 100 W/mK or more, said susceptor having a retaining side for retaining an object to be processed, said retaining side having a warpage of 500 μ m or less;

a resistive heating element incorporated in said susceptor, said resistive heating element patterned in a circuit having a pattern spacing of 0.1 mm or more; and

a metal plate having a thermal conductivity of 100 W/mK or more higher than that of said ceramic susceptor, said metal plate mechanically attached to said susceptor opposite said retaining side by an adhesive bonding layer, by screws screwed into said susceptor, or by a recess provided in said metal plate, into which said susceptor is snug-fit, for whereby the higher thermal conductivity of said metal plate than, together with said metal plate's mechanical attachment to, said susceptor promote[[ing]] diffusion of heat from said resistive heating element toward said retaining side.

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Claim 2 (original): A holder as set forth in claim 1, wherein said metal plate and said ceramic susceptor are fastened by bonding, screws, snug-fitting, or vacuum adhesion.

Claim 3 (original): A holder as set forth in claim 1, wherein the resistive heating element is present beyond the middle in the thickness direction of said susceptor, toward the side opposite said retaining side.

Claim 4 (original): A holder as set forth in claim 1, wherein the ceramic of said ceramic susceptor is any one selected from Al₂O₃, SiO₂, B₄C and BN.

Claim 5 (canceled)

Claim 6 (previously presented): A holder as set forth in claim 1, wherein the ceramic of said ceramic susceptor is any one selected from AIN, SiC and Si₃N₄.

Claim 7 (canceled)

Claim 8 (previously presented): A holder as set forth in claim 1, wherein said metal is any one selected from Al-SiC, Cu-W and Cu-Mo.

Claim 9 (original): A holder as set forth in claim 1, wherein the thickness of said metal plate is thicker than the thickness of said ceramic susceptor.

Claim 10 (original): A holder as set forth in claim 1, wherein the diameter of said ceramic susceptor is 200 mm or more.

Claim 11 (original): A holder as set forth in claim 1, wherein the porosity of the ceramic of said ceramic susceptor is 0.03% or less.

Claim 12 (canceled)

Claim 13 (original): A semiconductor manufacturing device in which the

holder of claim 1 is installed.

Claim 14 (original): A liquid-crystal manufacturing device in which the holder

of claim 1 is installed.

Claim 15 (currently amended): A holder for semiconductor as well as liquid-

crystal manufacturing devices, the holder comprising:

a ceramic susceptor of a ceramic of porosity of 0.03% or less and whose

thermal conductivity is 100 W/mK or more, said susceptor having a retaining side for

retaining an object to be processed, said retaining side having a warpage of 500 µm

or less;

a resistive heating element incorporated in said susceptor, said resistive

heating element patterned in a circuit having a pattern spacing of 0.1 mm or more;

and

a metal plate made of one selected from Al-SiC, Cu-W and Cu-Mo to have a

thermal conductivity greater than that of said susceptor, said metal plate fastened to

said susceptor opposite said retaining side by an adhesive bonding layer, by screws

screwed into said susceptor, or by a recess provided in said metal plate, into which

said susceptor is snug-fit, for whereby the higher thermal conductivity of said metal

plate than, together with said metal plate's mechanical attachment to, said susceptor

promote[[ing]] promoting diffusion of heat from said resistive heating element toward

said retaining side.

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Claim 16 (currently amended): A holder for semiconductor as well as liquid-

crystal manufacturing devices, the holder comprising:

a ceramic susceptor 200 mm or more in diameter, of a ceramic of porosity of

0.03% or less and whose thermal conductivity is 100 W/mK or more, said susceptor

having a retaining side for retaining an object to be processed, said retaining side

having a warpage of 500 μ m or less;

a resistive heating element incorporated in said susceptor and therein present

beyond the middle in the thickness direction of said susceptor, toward the side

opposite said retaining side, said resistive heating element patterned in a circuit

having a pattern spacing of 0.1 mm or more; and

a metal plate made of one selected from Al-SiC, Cu-W and Cu-Mo to have a

thermal conductivity greater than that of said susceptor, said metal plate fastened to

said susceptor opposite said retaining side by an adhesive bonding layer, by screws

screwed into said susceptor, or by a recess provided in said metal plate, into which

said susceptor is snug-fit, for whereby the higher thermal conductivity of said metal

plate than, together with said metal plate's mechanical attachment to, said susceptor

promote[[ing]] diffusion of heat from said resistive heating element toward said

retaining side.

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